

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 217470US6PCT	SERIAL NO. 10/030,272		
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Olivier RAYSSAC, et al.			
				FILING DATE January 8, 2002	GROUP 1755		
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT & TRADEMARK NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
MAO	AA	5,029,418	07/09/91	D. N. BULL	—	—	
MAO	AB	3,918,150	11/11/75	F. C. GANTLEY	—	—	
MAO	AC	5,863,375	01/26/99	G-H. CHA, et al	—	—	
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
MAO	AO	0 925 888	06/30/99	EUROPE			
MAO	AP	62-230537	10/09/87	JAPAN (submitting English Abstract only)			
MAO	AQ	2 752 332	02/13/98	FRANCE (with English Abstract)		X	
MAO	AR	WO 98/52216	11/19/98	WIPO			
MAO	AS	0 703 609	03/27/96	EUROPE (with English Abstract)		X	
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
MAO	AW	W. P. MASZARA, et al., J. Appl. Phys, Vol. 64, No. 10, pps. 4943-4950, "BONDING OF SILICON WAFERS FOR SILICON-ON-INSULATOR", November 15, 1988					
MAO	AX	C. MALEVILLE, et al., Electrochemical Society Proceedings, Vol. 97-36, pps. 46-55					
MAO	AY	O. RAYSSAC, et al., 2 nd International Conference on Materials for Micro-Electronics, pps. 183-191, "INFLUENCE OF SURFACE CHARACTERISTICS ON DIRECT WAFER BONDING", September 14/15, 1998					
	AZ						
Examiner	Mark A. Oseke			Date Considered 5-29-03			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							